

FORM PTO 1449 (modified) U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE LIST OF REFERENCES CITED BY APPLICANT(S) (Use several sheets if necessary)				ATTY DOCKET NO. 03500.017986.		APPLICATION NO. 10/550,450	
				APPLICANT YOSHIKATSU ICHIMURA, et al.			
				FILING DATE September 26, 2005		GROUP 2858	
U.S. PATENT DOCUMENTS							
*EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
JZ		4,205,267	05/1980	Williams	324	458	
		5,212,451	05/1993	Werner, Jr.	324	458	
		5,504,356	04/1996	Takeuchi, et al.	257	254	
		2003/0057977	03/2003	Werner, Jr., et al.	324	754	
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FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES/NO/ OR ABSTRACT
JZ		2715831	10/1978	Germany			No
		10044887	05/2001	Germany			Abstract
		1003044	05/2000	Europe			
		2-071166	03/1990	Japan			Abstract
		4-025764	01/1992	Japan			Abstract
		6-196721	07/1994	Japan			Abstract
		6-196722	07/1994	Japan			Abstract
OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.)							
JZ		HSU C. H. et al: "Micromechanical electrostatic voltmeter "TRANSDUCERS. SAN FRANCISCO, JUNE 24-27, 1991, PROCEEDINGS OF THE INTERNATIONAL CONFERENCE ON SOLID STATE SENSORS AND ACTUATORS, NEW YORK, IEEE, US, vol. CONF. 6, 24 JUNE 1991 (1991-06-24), pages 659-662					
JZ		RIEHL P.S. "Microsystems for Electrostatic Sensing" DISSERTATION, Online! November 2002 (2002-11) Page 1-8, 32-40, 79-84 (http://www-bsac.eecs.berkeley.edu/publications/search/zoom.php?urltimestamp=1040564878)					
EXAMINER				DATE CONSIDERED			
/John Zhu/				01/11/2007			

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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